

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

**priority** Application Serial No. ....09/943,186  
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**priority** Filing Date .....August 29, 2001  
Inventor..... John F. Van Itallie et al.  
Assignee..... Micron Technology, Inc.  
Group Art Unit.....unknown  
Examiner .....unknown  
Attorney's Docket No. ....MI22-2458  
Customer No. ....021567  
Title: Photolithographic Methods Of Using A Single Reticle To Form Overlapping Patterns

**PRELIMINARY AMENDMENT**

To: Mail Stop Patent Application  
Commissioner for Patents  
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**AMENDMENTS**